

# In<sub>x</sub>Ga<sub>1-x</sub>As High-Electron Mobility Transistors for Terahertz frequency applications

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**Abstract**—This paper reviews the state-of-the art In<sub>x</sub>Ga<sub>1-x</sub>As high electron mobility transistors (HEMTs) for future terahertz frequency operations, aiming to propose roadmap of next-generation In<sub>x</sub>Ga<sub>1-x</sub>As HEMT technology. We propose the physics-based compact model for device RF performance such as current gain cut-off frequency ( $f_T$ ) and maximum oscillation frequency ( $f_{max}$ ). Also, we quantitantly predict the device performance of sub-30 nm In<sub>x</sub>Ga<sub>1-x</sub>As HEMTs with innovatively improving parasitic resistance ( $R_s$ ) and capacitances components to reach  $f_T/f_{max}$  over 1 THz.

**Keywords**—InGaAs, compound semiconductor, HEMTs, cut-off frequency ( $f_T$ ), maximum oscillation frequency ( $f_{max}$ )

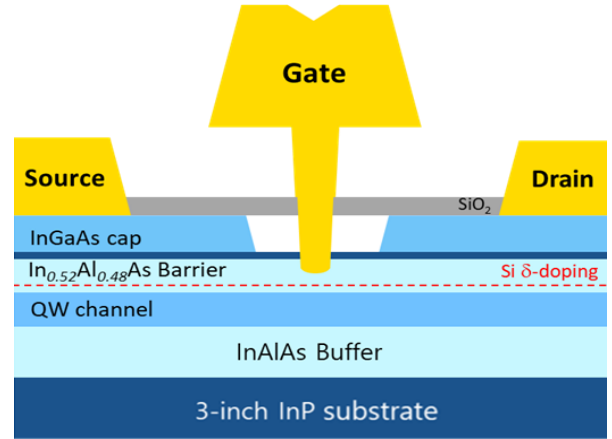
## I. Introduction

For several decades, semiconductor-based Terahertz (THz) microelectronics promise to introduce new areas of research and applications in the sub-millimeter-wave region (sub-MMW) and beyond [1-4]. In order to fully benefit the sub-MMW band, it is essential to develop semiconductor transistor technologies with both current gain cut-off frequency ( $f_T$ ) and maximum oscillation frequency ( $f_{max}$ ) close to 1 THz. To improve high-frequency characteristics of semiconductor transistor, historically, a path to improve  $f_T/f_{max}$  in InGaAs high-electron-mobility transistors (HEMTs) was to reduce the physical gate length ( $L_g$ ) down to sub-30 nm, while minimizing all of the parasitic components such as series resistance and gate-fringing capacitance. The other is to introduce high carrier mobility channel material. In this regard, indium-rich In<sub>x</sub>Ga<sub>1-x</sub>As HEMTs have offered the best balance of  $f_T$  and  $f_{max}$  to date [5-6].

## II. Developments and Analysis in InGaAs HEMTs

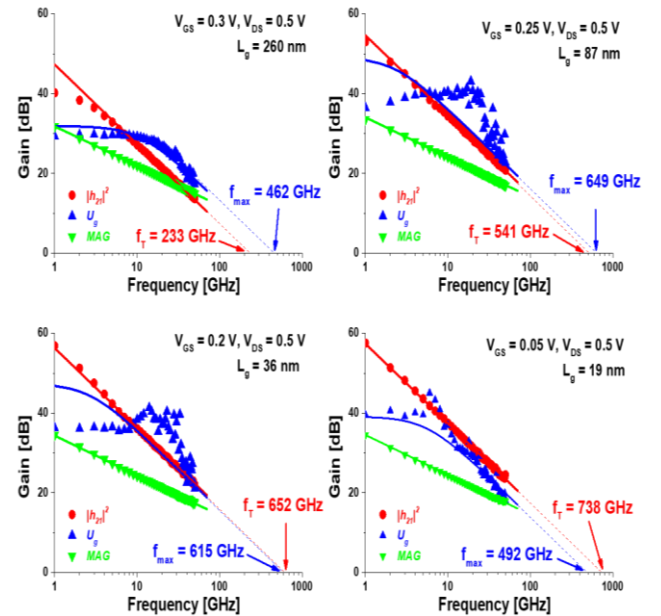
### A. State-of-the art InGaAs HEMTs

**Figure 1** shows the cross sectional schematic view of a conventional In<sub>x</sub>Ga<sub>1-x</sub>As HEMT. Semi-insulating (S.I) InP wafer of 3-inch size is commonly used in the fabrication of In<sub>x</sub>Ga<sub>1-x</sub>As HEMTs. It is imperative to develop InGaAs HEMTs of gate length less than 30 nm for terahertz wave applications. In<sub>x</sub>Ga<sub>1-x</sub>As HEMT technology could already achieve a  $f_T$  of 738 GHz [5] and  $f_{max}$  over 1 THz [3] which raises the hope for its use in future terahertz wave applications. **Figure 2** plots  $|h_{21}|^2$  and  $U_g$  for state-of-the art HEMT technology with various QW channel structure and gate length scaling from 300 to 20 nm [5]. As expected, both  $f_T$  and  $f_{max}$

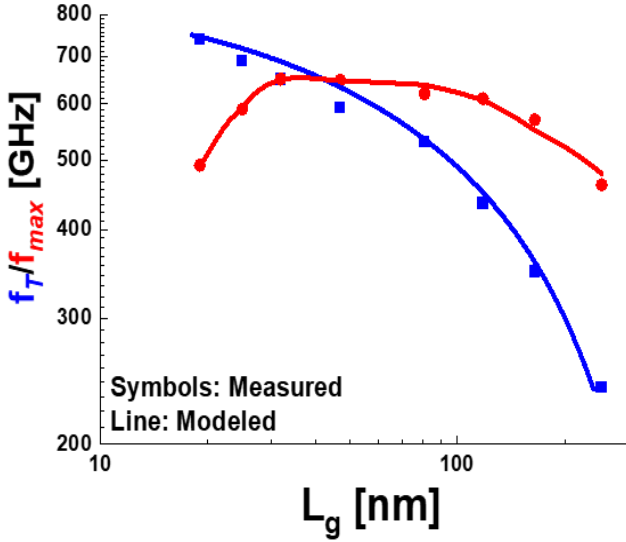


**Figure 1.** Schematic of conventional In<sub>x</sub>Ga<sub>1-x</sub>As HEMT.

improved with reduction of  $L_g$ . The composite-In<sub>0.8</sub>Ga<sub>0.2</sub>As HEMT demonstrated the values of  $f_T = 738$  GHz and  $f_{max} = 492$  GHz. **Figure 3** shows the dependence of  $f_T$  and  $f_{max}$  for all the devices upon  $L_g$ .



**Figure 2.** Measured RF gains ( $|h_{21}|^2$ ,  $U_g$  and MAG) versus frequency near the  $g_m$  peak gate voltage and at  $V_{DS} = 0.5$  V.



**Figure 3.** Measured (symbols) and modeled (lines)  $f_T/f_{max}$  against  $L_g$ .

#### B. $f_T/f_{max}$ physical model

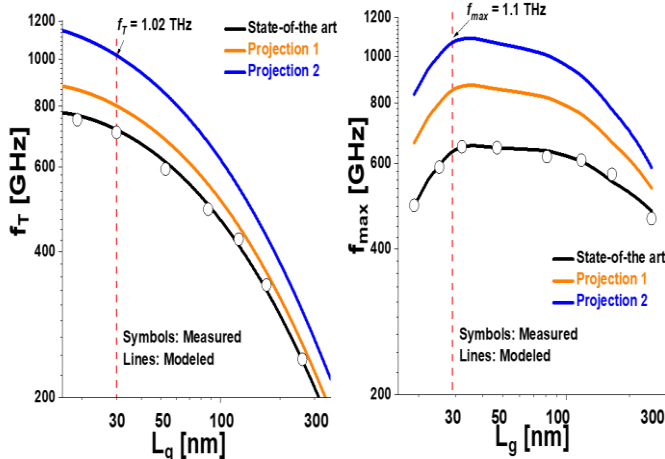
In an effort to understand the scaling behavior of  $f_T$  and  $f_{max}$ , the compact  $f_T/f_{max}$  physical model using physical/geometrical parameters. The first-order expressions for  $f_T$  and  $f_{max}$  are given as follows [7-8]:

$$f_T = \frac{1}{2\pi} \frac{g_{mi}}{C_{gs} + C_{gd} + g_{mi}(R_S + R_D)} \left\{ C_{gs} + (C_{gs} + C_{gd}) \frac{g_{ai}}{g_{mi}} \right\} \quad (1)$$

$$f_{max} = \frac{f_T}{2 \sqrt{(R_i + R_s + R_g) \cdot g_{oi} + (2\pi f_T) \cdot R_g \cdot C_{gd}}} \quad (2)$$

The values of  $g_{mi}$ ,  $R_S$ , and  $R_D$  were extracted as in  $R_S$  analysis [9] and  $g_m$  physical modeling [10], and  $g_{oi}$  was given by the product of  $g_{mi}$  and  $DIBL$  was used. As in [5],  $C_{gs}$  consisted of  $C_{gs\_areal} \times L_g$  (intrinsic) and  $C_{gs\_ext}$  (extrinsic) components, where  $C_{gs\_ext}$  was extracted separately at a pinch-off bias condition since  $C_{gs}$  was dominated by extrinsic components. The same analysis was performed for  $C_{gd}$ .

Modeled  $f_T$  and  $f_{max}$  are included as lines in **Figure 3**, where the approach in this work explains the dependence of  $f_T$  and  $f_{max}$  of all the devices upon  $L_g$  from 300 to 20 nm. The proposed  $f_T/f_{max}$  model is capable of explaining the measured  $f_T$  and  $f_{max}$  for all the devices universally.



**Figure 4.**  $f_T/f_{max}$  modeling result of device technology improvement (model projection).

### III. $\text{In}_x\text{Ga}_{1-x}\text{As}$ HEMTs for terahertz $f_T/f_{max}$ performance

The proposed physical  $f_T/f_{max}$  model accurately explain the measured  $f_T/f_{max}$  for all of  $L_g$ . So, by using physical  $f_T/f_{max}$  model, projection of the  $f_T/f_{max}$  characteristics of a device with improvement such as carrier transport property, reduction of  $R_S$ , and  $g_{oi}$  improvement, could be compared to current state-of-the-art  $\text{In}_x\text{Ga}_{1-x}\text{As}$  HEMTs devices. In projection 1, when  $R_S$  was reduced by 30%, it can be projected to improvement of about 15 % compared to conventional state-of-the-art devices with  $f_T/f_{max} = 800/870$  GHz at  $L_g = 30$  nm. In projection 2, when  $R_S$  and extrinsic gate capacitance ( $C_{g\_ext}$ ) were reduced to less than half, projected a value of  $f_T/f_{max}$  is 1.02/1.09 THz with improvement of about 40 % compared to state-of-the-art  $\text{In}_x\text{Ga}_{1-x}\text{As}$  HEMT device. **Figure 4** exhibit projection results of  $f_T/f_{max}$  as a function of  $L_g$  with current state-of-the-art HEMTs (black),  $R_S$  reduction (projection 1, orange),  $R_S$  and  $C_{g\_ext}$  reduction (projection 2, blue). For future THz operation device technology, it is important to demonstrate sub-30 nm  $\text{In}_x\text{Ga}_{1-x}\text{As}$  HEMTs with innovatively improving parasitic resistance components ( $R_s$ ) and, also, reduction of parasitic gate capacitance to reach  $f_T/f_{max}$  over 1 THz, as predicted  $f_T/f_{max}$  performance through physical modeling.

### IV. Conclusion

In this paper, we reviewed the state-of-the-art  $\text{In}_x\text{Ga}_{1-x}\text{As}$  high electron mobility transistors (HEMTs) for future terahertz frequency operations. Also, we modeled physically experimental RF FOMs (Figure of Merits) with state-of-the-art  $\text{In}_x\text{Ga}_{1-x}\text{As}$  HEMT technology. Also, we quantitatively predict the device performance of sub-30 nm  $\text{In}_x\text{Ga}_{1-x}\text{As}$  HEMTs with innovatively improving parasitic resistance components ( $R_s$ ) to reach  $f_T/f_{max}$  over 1 THz.

### ACKNOWLEDGMENT

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